

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.: **10/791,926** Examiner: **Emmanuel S. Luk**
Inventor: **Hong Hocheng and Chin Chung Nien**
Filed: **March 2, 2004** Art Unit: **1722**
Title: **Nano-Imprint System With Mold Deformation Detector And Method
Of Monitoring The Same**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT A

In response to the Office Action mailed **03/12/2007**, please amend the above-identified application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 4 of this paper.

Remarks begin on page 8 of this paper.